Constrained crystallization of poly(L-lactic acid) in thin films prepared by dip coating

Supplementary Material

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Figure SM 1 : AFM of PLLA100K in 1, 4 dioxane

Figure SM 1: AFM images of thin film obtained by dip coating a PLLA 100K solution in dioxane at different withdrawal speeds from 1 to 320 mm.min⁻¹. The withdrawal speeds in mm.min⁻¹ are indicated above the images.





Figure SM 2: AFM images of thin film obtained by dip coating a PLLA 323K solution in dioxane DCE at different withdrawal speeds from 1 to 320 mm.min⁻¹. The withdrawal speeds in mm.min⁻¹ are indicated above the images.

Figure SM 3: AFM of PLLA 323K in DCE







Figure SM 4: AFM images of thin film obtained by dip coating a PLLA 100K solution in DCM at different withdrawal speeds from 0.1 to 320 mm.min⁻¹. The withdrawal speeds in mm.min⁻¹ are indicated above the images

Figure SM 5: AFM of PLLA 323K in DCM







Figure SM 7: GIXRD diffractograms of the films of PLLA thin films obtained by dip coating solution in DCE, dioxane or DCM



Figure SM 8: AFM images of thin films of PLLA 100K DCE v=160 mm.min⁻¹ as a function of annealing steps





of annealing steps. The annealing procedure consists an addition of steps of 5 min annealing at increasing temperatures and quenching to room temperature .If the AFM images do not change between the steps, they are not shown. Initial morphology after dip coating a), After steps at 40 + at 50 + at 60°C b) + at 70°C c), + at 80, +at 90, +at 100, +at 110, +at 120, +at 130, +at 160 °C d), +at 180°C and quenching to room temperature e),+ at 180°C and decreasing slowly the temperature f).

Figure SM 9: GIXRD diffractograms of the films of PLLA thin films obtained by dip coating solution in DCE, dioxane or DCM



Figure SM10: AFM images of thin films of PLLA 100K DCE v=80 mm.min-1 as a function of solvent exposure annealing steps





Figure SM 11: AFM images of spin coated thin films of PLLA

Figure SM 12: AFM of thin film obtained by dip coating of solution of PLLA 100K, in DCE and DCM at withdrawal rate of 2 mm.min⁻¹

